## Surface dependent doping efficiency in Te:Cd<sub>3</sub>As<sub>2</sub> Thin films

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Cd<sub>3</sub>As<sub>2</sub> is a prototypical Dirac semi-metal, a class of materials with gapless topologically protected electronic states. In this system, these topological electronic states are close to the intrinsic Fermi level and are well isolated from non-trivial bands. Additionally, this system is air stable and compatible with molecular beam epitaxy, including lattice matching to III-Sb and II-Te layers, and similar elements to conventional semiconductors. These materials could play a role in a large number of applications, including transistors, spintronics, photodetectors, and thermoelectrics. To do this, however, significant progress must be made on achieving tunability of these materials. In particular, routes to altering its typical n-type carrier concentration must be developed.



Figure 1. Electron concentration vs dopant flux ratio in  $Cd_3As_2$  thin films of two different orientations

Previous attempts to dope  $Cd_3As_2(112)$  with group VI elements, including Te and Se, were successful, allowing for increases of n<sub>3d</sub> from  $5e17 \text{ cm}^{-3}$  up to slightly over  $3e18 \text{ cm}^{-3}$  [1]. Concentration vs mobility relationships appeared similar to doping in convention semiconductors, with mobility decreasing with increased ionized impurities. Attempts to increase doping beyond this level by using increased group VI fluxes resulted in lower measured Hall concentrations and even larger decreases in mobility, a sign that compensating defects are forming. When similar doping is attempted on the (001) surface, however, doping beyond 1e19 cm<sup>-3</sup> is possible. Furthermore, an order of magnitude smaller Te fluxes are required to achieve similar doping levels. Finally, smaller unintentionally doped

carrier concentrations are achievable on this surface. This work highlights the role of surface kinetics in defect incorporation in topological semi-metals.

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